Hitachi Anisotropic Conductive Film ANISOLM®

AC-823CY-20

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Display Materials Div.

Display Materials R&D Dept.

Hitachi Chemical Co.,Ltd.



< NOTICE: This document may wholly or partially be subject to change without notice.>

1. Standard specification, bonding condition, storage condition and characteristic

cations	apability in erconnection circuit	Connection area Insulation gap	um²	800 12 7	Min. contact area (Including Msalignment) Bump Electrode (ITO, Metal etc.) Ave3 $\sigma \ge 3$ pcs. Bump Glass IC Electrode (ITO, Metal etc.)	
inte	erconnection circuit Conductive particle		um		Glass (ITO , Metal etc.) Min. space	
Specifications O	particle		um	7	IC Electrode	
Specifica	particle	Size			Bump Glass (ITO, Metal etc.) Min. space (In Misalignment)	
Spec			um	3	Au coated plastic particle	
~ <u>2</u>	Thi	Density	pcs/mm ²	55,000	with insulation surface treatment	
dard	Thickness		um	20		
Stan	Width		mm	1.5, 2.0, 2.5, 3.0	Contact us for other width request	
	Length		m	50 / 100		
	Color		_	Transparent (gray)		
	Core diameter		mm	18.5		
	Configuration		-	Double-Layer ACF— Particle-filled layer Non particle-filled layer Separator (White PET 50um)		
	g To	emperature	degC	50 - 70	Final ANISOLM temperature	
Bonding conditions	lamination T	Pressure	MPa	1 - 1.5	Per unit area of ANISOLM	
iondi	lan	Time	S	1 - 2		
ling c	To To	emperature	degC	170 ± 10	Final ANISOLM temperature	
Bondir IC main	bonding	Pressure	MPa	30 - 120	Per total bump area	
	Ď	Time	S	5 or more	Including temp increasing time	
Storage conditions	Succession Unopened Unopened		_	4.5 months after date of manufacture when stored at -10 to 5degC.		
Sto		Opened	_	10 days at 25 degC or below and 70%RH or below.		

Notes:

The values given above represent typical measurements, not guaranteed ones.

¹⁾ Leave ANISOLM at room temperature for an hour before opening sealed bag. Make sure ANISOLM is not wet before using it

Suitable bonding condition depends on specification of IC chip, glass substrate, bonding machines etc. Please contact us for detailed information.

2. ACF Lamination process window

Checking issues before start of ACF Lamination process

- (1) Make sure adjustment to the depth and parallel of half cut knife edge in the ACF
- (2) Make sure adjustment to the bonding head position and select of cushion sheet

ACF: AC-823CY-20

Time	Temperature	Pressure [MPa]		
[s]	[degC]	0.5	1.0	1.5
	40	Δ/Ο	0/0	0/0
	50	0/0	0/0	0 / 0
1.0	60	0/0	0/0	0/0
1.0	70	0 / 0	0/0	0/0
	80	0 / 0	0 / △	0 / △
	90	O / ×	O / X	× / ×
	40	Δ/Ο	0/0	0/0
	50	0 / 0	0/0	0/0
1.5	60	0/0	0/0	0/0
1.5	70	0/0	0/0	0/0
	80	Ο / Δ	Ο / Δ	0 / △
	90	O / ×	O / X	× / ×
	40	0 / 0	0/0	0/0
	50	0/0	0/0	0/0
2.0	60	0/0	0/0	0/0
2.0	70	0/0	0/0	0/0
	80	Ο / Δ	O / X	O / X
	90	O / ×	O / X	× / ×

<u>Lamination property</u> / ACF Oozing property

O : Superior Result
 △ : A little Inferior Result
 × : Inferior Result

3. ACF Reaction rate

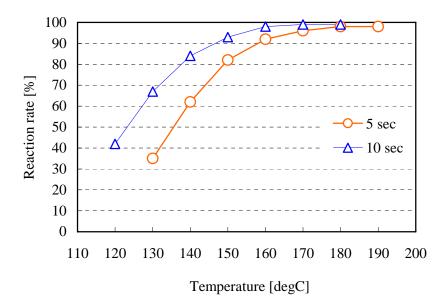
Measuring method:

Each specimen was heated and hardened in oil kept at a specified temperature for a specified time, the amount of heat generated was measured with a DSC unit, and the reaction rate was determined with the following formula;

Reaction rate = $(Q_0-Q_T)/Q_0 \times 100$

Q₀: initial amount of heat generated

Q_T: amount of heat generated after hardening



4. Bonding appearance depend on final bonding conditions

Measuring method:

/ Test chip : Bump size **2,500**um2 (<u>50 x 50um</u>), IC size: 1.7 x 17 x 0.55mm

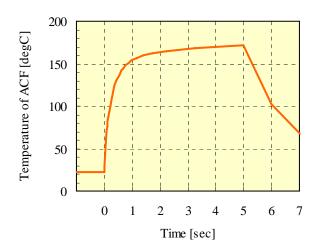
/ Test board: Al/Nd coated glass

/ Bonding condition: 160-170degC 30~150MPa 5sec

Glass Electrode	30 MPa	50 MPa	80 MPa	100 MPa	120 MPa
ITO (Particle Deformation)					100 mm = 100
Al/Nd (Particle Trace)					
Judgment	nent Excellent Excellent		Excellent	Excellent	Excellent

5. Precautions in bonding

5.1 Temperature profile in main-bonding of IC chip



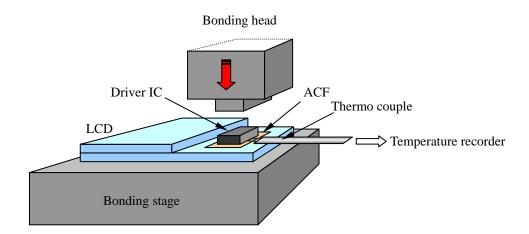
Ex.)

Bonding condition: 170 degC-5sec
Head setting temperature: 190 degC
Chip size: 1.7mm x 17.2mm x 0.55mmt
Thickness of glass substrate: 0.7mmt

Caution: Temperature should reach at more than 90% of targeting ACF temperature within

first 2 seconds.

5.2 Measurement of ANISOLM temperature



5.3 Bonding head

- (1) Make sure the coplanarity of bonding head is even and parallel to IC chip.
- (2) Use slightly wider head than IC chip. Example; Chip width 2.0mm → Head width 2.5mm

5.4 Misalignment of opposite circuits

Make sure opposite circuits are well aligned and matched each other.

6. Connection reliability

6.1 Measurement

(1) Used materials for measurement

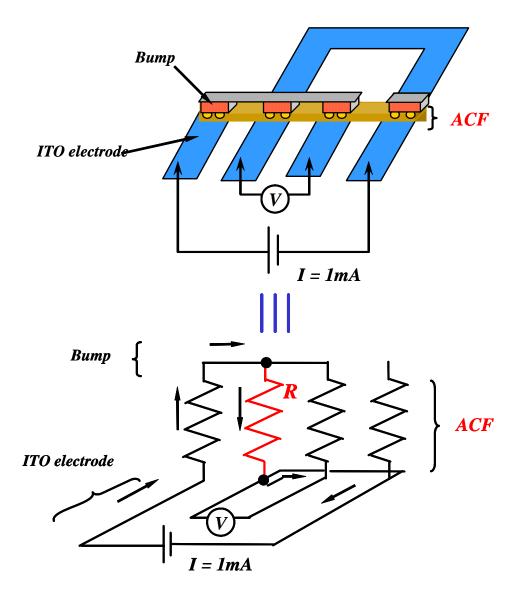
/ Test chip : Connection area **2,500**um2 (Bump size: 50 x 50um, IC size: 1.7 x 17 x 0.55mm)

/ Test board: ITO coated glass (ITO thickness: 0.2um, Surface resistance: 10ohm/sq)

(2) Measurement of connection resistance (refer to the diagram below)

/ Four-probe measurement (Circuit resistance can be cancelled)

/ Applied current: 1mA



Four probe measurement in COG interconnection

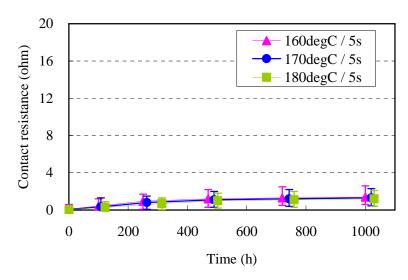
6.2 Test results

ACF: AC-823CY-20

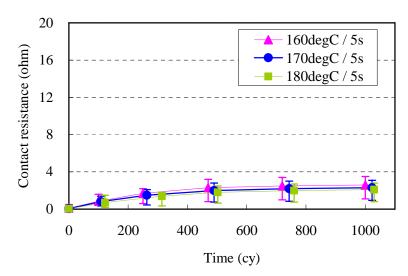
Lamination condition: 70degC 1MPa 2sec

Main bonding condition: 160 - 180degC 80MPa 5sec

(1) High temperature humidity test (85degC85%RH)



(2) Temperature cycling test (-40 / 100 degC)



7. Insulation reliability

7.1 Non-bias test

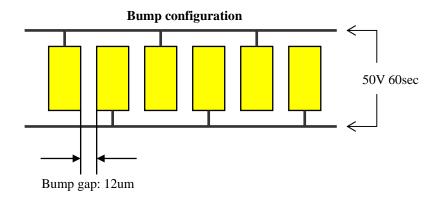
(1) Used materials for measurement

/ Test chip: Bump gap 12um (Bump size: 30 x 100um, IC size: 1.9 x 15 x 0.55mm)

/ Test board: ITO coated glass (ITO thickness: 0.2um, Surface resistance: 10ohm/sq)

(2) Measurement of insulation resistance

The resistance of each test piece was measured after applying 50V DC to it for 60 seconds in an atmosphere at 23degC and 65%RH.



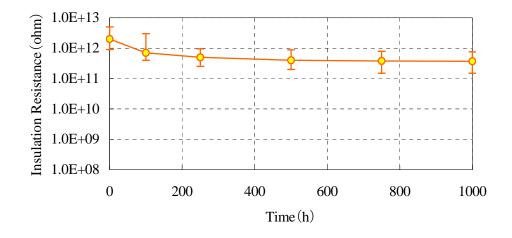
(3) Result

ACF: AC-823CY-20

Lamination condition: 70degC 1MPa 2sec

Main bonding condition: 170degC 80MPa 5sec

Test condition: 85degC85%RH



7.2 In-situ Bias test

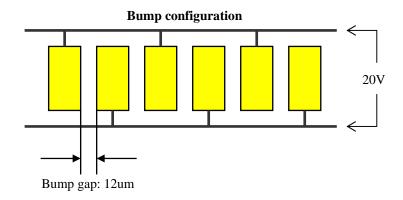
(1) Used materials for measurement

/ Test chip: Bump gap 12um (Bump size: 30 x 100um, IC size: 1.9 x 15 x 0.55mm)

/ Test board: ITO coated glass (ITO thickness: 0.2um, Surface resistance: 10ohm/sq)

(2) Test procedure

20V was continuously applied between comb shaped circuit during high temp humidity test and the insulation resistance was monitored by insulation resistance meter.



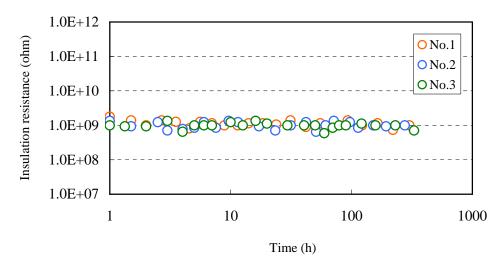
(3) Result

ACF: AC-823CY-20

Lamination condition: 70degC 1MPa 2sec

Main bonding condition: 170degC 80MPa 5sec

Test condition: 60degC90%RH



8. Particle counts data on bump

(1) Used materials for measurement

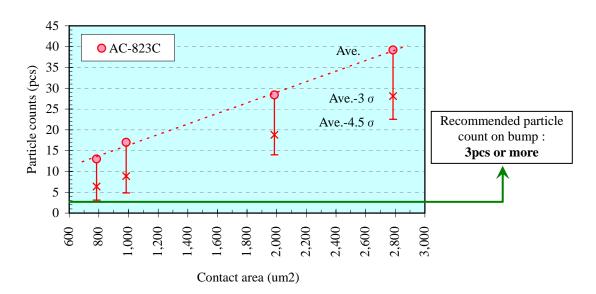
/ Test chip 1: Bump size **2,800**um2 (**28 x 100um**), IC size: 1.9 x 15 x 0.55mm

/ Test chip 2: Bump size **2,000**um2 (**20 x 100um**), IC size: 1.6 x 15 x 0.55mm)

/ Test board: ITO coated glass(ITO thickness: 0.2um, Surface resistance: 10ohm/□)

(2) Measurement of particle counts on bump

After main bonding IC chip onto test glass, particle count on bump was measured by optical microscope. The data at 1,000um2 and 800um2 were calculated value based on the actual data at 2,000um2 and 2,800um2 bump size.



9. Physical properties

Item	Unit	AC-823C
Tg *1	degC	135
Elastic modulus	GPa	1.8
C.T.E *2	ppm/degC	60
Water absorption rate	wt%	1.0

Conditions

*1 Measured with DVE; Dynamic Visco-Elastic Analyzer

Test conditions: Fully cured sample, Tensile mode, 10Hz Frequency, 10degC/min

*2 Measured with TMA; Thermal Mechanical Analyzer

Test conditions: Fully cured sample, Tensile mode, 10degC/min, Load 5gf